

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Makoto IIDA et al.

Application No.: 10/586,953

Filed: July 25, 2006

For: A SILICON SINGLE CRYSTAL, A SILICON
WAFER, AN APPARATUS FOR PRODUCING
THE SAME, AND A METHOD FOR
PRODUCING THE SAME



Group Art Unit: 1714

Examiner: G. RAO

Docket No.: 128832

MAIL STOP RCE

**LARGE ENTITY REQUEST FOR
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicants hereby request continued examination.

☒ Applicants further request entry and consideration of the submission filed June 24, 2010.

The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 230569 in the amount of ☒ \$810.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Commissioner is hereby authorized to charge any additional fees or credit any overpayment associated for this filing to Deposit Account No. 15-0461.

Respectfully submitted,

William P. Berridge
Registration No. 30,024

Tommy T. Kim
Registration No. L0543

WPB:TTK/mms

Date: July 15, 2010

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**DEPOSIT ACCOUNT USE
AUTHORIZATION**

Please grant any extension
necessary for entry of this filing;
Charge any fee due to our
Deposit Account No. 15-0461

07/16/2010 AWONDAF1 00000079 10586953

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